OCT 1 5 2002 E

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Zheng, et al.

Serial No.: 09/614,407

Confirmation No.: 1903

Filed:

July 12, 2000

For:

Method of Application of

Electrical Biasing to Enhance

Metal Deposition

Box RCE

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

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Group Art Unit: 1741

Examiner:

Smith-Hicks, E.

CERTIFICATE UNDER 37 CFR 1.10

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on 10-15, 2002 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV0155454088US addressed to: Box RCE, Commissioner for Patents, Washington, D.C. 20231.

10(15)02 Date

Signature

PRELIMINARY AMENDMENT

Applicants, in accordance with 37 C.F.R. §1.114(c), request consideration of the following amendments prior to the examination of the attached Request for Continued Prosecution of the above identified application.

IN THE CLAIMS:

Please add the following new claims:

85. (New) A method of depositing a metal on a substrate having one or more features formed thereon, comprising:

applying a first biasing voltage to the substrate while immersing the substrate into an electrolyte solution contained in an electrolyte container comprising an anode immersed in the electrolyte solution, wherein the first biasing voltage increases over

time; and

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